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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/869,347	09/07/2001	Takeshi Uchida	566.40319X00	4090
7590 01/12/2005			EXAMINER	
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1300 North Seventeenth Street			ART UNIT	PAPER NUMBER
Arlington, VA 22209			2813	

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Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)			
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Office Action Summary	09/869,347 Examiner	UCHIDA ET AL. Art Unit			
	Laura M. Schillinger	2813			
The MAILING DATE of this communication app					
Period for Reply					
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period we Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	6(a). In no event, however, may a reply be t within the statutory minimum of thirty (30) da ill apply and will expire SIX (6) MONTHS froi cause the application to become ABANDON	imely filed ays will be considered timely. m the mailing date of this communication. ED (35 U.S.C. § 133).			
Status		·			
1) Responsive to communication(s) filed on 03 Ja	nuary 2005.				
3) Since this application is in condition for allowance except for formal matters, prosecution as to the ments is					
closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.					
Disposition of Claims					
4) ⊠ Claim(s) 1-73 is/are pending in the application. 4a) Of the above claim(s) 56-73 is/are withdraw 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) 1-55 is/are rejected. 7) □ Claim(s) is/are objected to. 8) □ Claim(s) are subject to restriction and/or					
Application Papers					
9) The specification is objected to by the Examine	r.				
10) ☐ The drawing(s) filed on is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.					
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).					
Replacement drawing sheet(s) including the correcti 11) The oath or declaration is objected to by the Ex					
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau * See the attached detailed Office action for a list of	s have been received. s have been received in Applica ity documents have been receiv i (PCT Rule 17.2(a)).	ntion No ved in this National Stage			
Attachment(s)					
 Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date <u>2/2/04;3/31/04</u>. 	4) Interview Summal Paper No(s)/Mail I 5) Notice of Informal 6) Other:				

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DETAILED ACTION

Election/Restrictions

Newly submitted claims 56-73 directed to an invention that is independent or distinct from the invention originally claimed for the following reasons: Claims 56, 62, 68 and their respective dependent claims constitute a separate and distinct species from the originally elected claims.

Since applicant has received an action on the merits for the originally presented invention, this invention has been constructively elected by original presentation for prosecution on the merits. Accordingly, claims 56-73 are withdrawn from consideration as being directed to a non-elected invention. See 37 CFR 1.142(b) and MPEP § 821.03.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1-55 are rejected under 35 U.S.C. 102(e) as being anticipated by Kaufman et al ('997).

In reference to claim Kaufman et al teaches a metal-polishing liquid material comprising an oxidized metal etchant (Col.6, lines: 25-31), a protective film forming agent (Col.5, lines: 45-65), and a dissolution promoter for the protective film forming agent (Col.6, lines: 30-45)

In reference to claim 2, Kaufman et al teaches further comprising at least one of an oxidizing agent (Col.5, lines: 25-45).

In reference to claim 3, Kaufman et al teaches comprising the ingredient group consisting of the oxidizing agent, the oxidized metal etchant, the protective film forming agent and the dissolution promoter in a divided state into two constituent elements not mixed (Col.8, lines: 50-65).

In reference to claim 4, Kaufman et al teaches wherein the dissolution promoter is a surfactant (Col.6, lines: 30-45).

In reference to claim 5, Kaufman et al teaches wherein the surfactant is at least one of: esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

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In reference to claim 6, Kaufman et al teaches wherein the dissolution promoter is a solvent in which the solubility of the protective film-forming agent is at least 25 g/liter (inherent).

In reference to claim 7, Kaufman et al teaches wherein the solvent is a good solvent for the protective film-forming agent (Col.6, lines: 30-45).

In reference to claim 8, Kaufman et al teaches wherein the solvent is at least one of alcohols, ethers and ketones ethers (ethyleme glycol) (Col.6, lines 60-69).

In reference to claim 9, Kaufman et al teaches wherein the amount of the solvent is smaller than 50g relative to 100 g of a total amount of the material (Col.6, lines: 55-60).

In reference to claim 10, Kaufman et al teaches wherein at least a part of the protective film-forming agent is solid having a mean particle size of at most 100 um (Col.7,lines: 50-60).

In reference to claim 11, Kaufman et al teaches further comprising abrasive grains (Col.7, lines: 50-60).

In reference to claim 12, Kaufman et al teaches a metal-polishing liquid which comprises an oxidizing agent (Col.5, lines: 25-40) an oxidized metal etchant (Col.6, lines: 25-31), a protective film forming agent protective film forming agent (Col.5, lines: 45-65), a

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dissolution promoter for the promoter (Col.6, lines: 35-45) for the protective film forming agent, and water (Col.8, lines: 45-50).

In reference to claim 13, Kaufman et al teaches wherein the dissolution promoter is surfactant (Col.6, lines: 35-45).

In reference to claim 14, Kaufman et al teaches wherein the dissolution promoter is a solvent in which the solubility of the protective film forming agent is at least 25 g/liter (inherent).

In reference to claim 15, Kaufman et al teaches wherein at least a part of the protective film forming agent is solid, having a mean particle size of at most 100 um (Col.7, lines: 55-60).

In reference to claim 16, Kaufman et al teaches further comprising abrasive grains (Col.7, lines: 55-60).

In reference to claim 17, Kaufman et al teaches a method comprising a step of diluting the metal-polishing liquid material of claim 2 with a diluent (Col.8, lines: 45-50).

In reference to claim 18, Kaufman et al teaches comprising the step of diluting a metalpolishing liquid material comprising at least one ingredient of an ingredient group consisting of an oxidizing agent (Col.5, lines: 25-40), the oxidized metal etchant (Col.6,

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lines: 25-30)), the protective film forming agent (Col.5, lines: 50-65) and the dissolution promoter (Col.6, lines: 35-45), with an aqueous solution for dilution of at least one ingredient of the ingredient group (Col.8, lines: 45-50)

In reference to claim 19, Kaufman et al teaches a method comprises the step of mixing the following:

A first constituent element that contains at least one ingredient of an ingredient group consisting of an oxidizing agent (Col.5, lines: 25-40), an oxidized metal etchant (Col.6, lines: 25-30), a protective film forming agent (Col.5, lines: 50-65) and a dissolution promoter for the protective film-forming agent(Col.6, lines: 35-45);

A second constituent element that contains at least one of the other ingredients of the ingredient group (Col.8, lines: 55-65);

A diluent (Col.8, lines: 45-50);

Wherein at least one of the first and second element includes a dissolution promoter for the protective film forming agent. (Col.8, lines: 55-65).

In reference to claim 20, Kaufman et al teaches wherein the diluent is water or an aqueous diluent solution (Col.8, lines: 45-50).

In reference to claim 21, Kaufman et al teaches wherein a first constituent element that contains at least one ingredient of an ingredient group consisting of an the oxidizing

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agent (Col.5, lines: 25-40), an oxidized metal etchant (Col.6, lines: 25-30), a protective film forming agent (Col.5, lines: 45-65) and a dissolution promoter for the protective film-forming agent(Col.6, lines: 35-45).

In reference to claim 22, Kaufman et al teaches wherein the first constituent element further comprises the protective film forming agent and a dissolution promoter for the protective film-forming agent(Col.8, lines: 55-65).

In reference to claim 23, Kaufman et al teaches wherein in the mixing step, the oxidizing agent and the oxidizing agent containing mixture are kept at a temperature at most 40 °C (Col.8 lines: 55-65-does not teach to heat therefore assumed to be at room temperature).

In reference to claim 24, Kaufman et al teaches wherein at least a part of the protective film-forming agent is solid, having a mean particle size of at most 100 um, and is dissolved or dispersed in the metal-polishing liquid in the mixing step (Col.7, lines: 55-60).

In reference to claim 25, Kaufman et al teaches a method comprising a polishing step of:

Applying the metal-polishing liquid of claim 12 to a polishing pad set on a platen (Col.4, liens: 30-35)), and

Polishing the surface of an article to be polished with the polishing pad by moving the polishing pad and the surface of the article relatively to each other while keeping the surface of the article in contact with the polishing pad (Col.4, lines: 30-35).

In reference to claim 26, Kaufman et al teaches further comprising a mixing step prior to the polishing wherein:

A first constituent element that contains at least one ingredient of an ingredient group consisting of an oxidizing agent (Col.5, lines: 25-40), an oxidized metal etchant (Col.6, lines: 25-30), a protective film forming agent (Col.5, lines: 50-65) and a dissolution promoter for the protective film-forming agent(Col.6, lines: 35-45);

A second constituent element that contains at least one of the other ingredients of the ingredient group (Col.8, lines: 55-65);

A diluent (Col.8, lines: 45-50);

In any desired order (Col.8, lines: 55-65).

In reference to claim 27, Kaufman et al teaches wherein the dissolution promoter is a surfactant (Col.6, lines: 35-45).

In reference to claim 28, Kaufman et al teaches wherein the surfactant is at least one of: esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

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In reference to claim 29, Kaufman et al teaches wherein the dissolution promoter is a solvent in which the solubility of the protective film-forming agent is at least 25 g/liter (inherent).

In reference to claim 30, Kaufman et al teaches wherein the solvent is a good solvent for the protective film-forming agent (Col.6, lines: 30-45).

In reference to claim 31, Kaufman et al teaches wherein the solvent is at least one of alcohols, ethers and ketones ethers (ethyleme glycol) (Col.6, lines:60-69).

In reference to claim 32, Kaufman et al teaches wherein the amount of the solvent is smaller than 50g relative to 100 g of a total amount of the material (Col.6, lines: 55-60).

In reference to claim 33, Kaufman et al teaches wherein at least a part of the protective film-forming agent is solid having a mean particle size of at most 100 um (Col.7, lines: 50-60).

In reference to claim 34, Kaufman et al teaches further comprising abrasive grains (Col.7, lines: 50-60).

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In reference to claim 35, Kaufman et al teaches a method comprising a step of diluting the metal-polishing liquid material of claim 1 with a diluent (Col.8, lines: 45-50).

In reference to claim 36, Kaufman et al teaches wherein the diluent is water or an aqueous diluent solution (Col.8, lines: 45-50).

In reference to claim 37, Kaufman et al teaches wherein the dissolution promoter promotes dissolving the protective film forming agent in water (Col.6, lines: 35-45).

In reference to claim 38, Kaufman et al teaches wherein each ingredient of the ingredient of said ingredient group is a different ingredient (Col.8, lines: 55-65).

In reference to claim 39, Kaufman et al teaches wherein the protective film forming agent, the dissolution promoter, the oxidized metal etchant, the oxidizing agent and water are different ingredients (Compare- Col.5, lines: 25-40, 45-65, Col.6, lines; 25-30 and Col.6, lines: 35-45 and 60-69).

In reference to claim 40 Kaufman et al teaches wherein the protective film forming agent is selected from the group of azoles (Col.5, lines: 45-65).

In reference to claim 41, Kaufman et al teaches wherein the dissolution promoter is a sufuctant or solvent (Col.6, lines: 35-45).

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In reference to claim 42, Kaufman et al teaches wherein the dissolution promoter is a surfactant (Col.6, lines: 35-45).

In reference to claim 43, Kaufman et al teaches wherein the surfactant is at least one of esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

In reference to claim 44, Kaufman et al teaches wherein the dissolution promoter is a solvent for the protective film forming agent in which the solubility is at least 25 g/liter (inherent).

In reference to claim 45, Kaufman et al teaches wherein the dissolution promoter is at least an esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

In reference to claim 46, Kaufman et al teaches wherein the solubility of the film forming agent is 40 g/l (inherent property of material).

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In reference to claim 47, Kaufman et al teaches wherein the solubility of the film forming agent is 50 g/l (inherent property of the material).

In reference to claim 48, Kaufman et al teaches wherein the protective film forming agent is selected from the group of azoles (Col.5, lines: 45-65).

In reference to claim 49, Kaufman et al teaches wherein the dissolution promoter is a surfactant (Col.6, lines: 35-45).

In reference to claim 50, Kaufman et al teaches wherein the dissolution promoter is a surfactant (Col.6, lines: 35-45).

In reference to claim 51 Kaufman et al teaches wherein the dissolution promoter is at least an esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

In reference to claim 52, Kaufman et al teaches wherein the dissolution promoter is a solvent for the protective film forming agent in which the solubility is at least 25 g/liter (inherent property of the material).

In reference to claim 53, Kaufman et al teaches wherein the dissolution promoter is at least an esters ethers, polysaccharides, salts of amino acids, polycarboxylic acids, salts of

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polycarboxylic acids, vinyl polymers, sulfonic acids, sulfonates, and amides (Col.6, lines: 30-45 and 60-69).

In reference to claim 54, Kaufman et al teaches wherein the solubility of the film forming agent is 40 g/l (inherent property of the material).

In reference to claim 55, Kaufman et al teaches wherein the solubility of the film forming agent is 50 g/l (inherent property of the material).

Response to Arguments

Applicant's arguments with respect to claims 1-55 have been considered but are most in view of the new ground(s) of rejection.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Laura M. Schillinger whose telephone number is (571) 272-1697. The examiner can normally be reached on M-T, R-F 7:00-5:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl W. Whitehead, Jr. can be reached on (571) 272-1702. The fax phone

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number for the organization where this application or proceeding is assigned is 703-872-9306.

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LMS

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